

Docket No.: 4539-0116PUS1
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Ken NAKANISHI

Application No.: 10/588,164

Confirmation No.: 4109

Filed: August 1, 2006

Art Unit: 2826

For: ION DOPING APPARATUS, ION DOPING
METHOD, SEMICONDUCTOR DEVICE AND
METHOD OF FABRICATING
SEMICONDUCTOR DEVICE

Examiner: E. T. Pert

REPLY TO RESTRICTION REQUIREMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Madam:

In reply to the Restriction Requirement dated June 10, 2009, the following remarks are respectfully submitted in connection with the above-identified application.

This reply includes **Remarks**.